

Application No.: 10/623,958
Date of Response: 09/02/2004
Reply to Action of: 08/20/2004

Application No.	10/623,958
Applicant	Mandina, Michael P.
Filed	8/20/2004
Title	Apparatus and Process for Polishing a Substrate
TC/A.U.	3723
Examiner	Rachuba, Maurina T
Docket No.	MPM-560

Honorable Commissioner for Patents
P.O. Box 1450
5 Alexandria, VA 22313-1450

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ELECTION

Sir:

In reply to the Office Action of August 20, 2004, please find the response

10 as follows:

Election begins on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.

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ELECTION

In response to the Office Communication of August 20, 2004, in which the Examiner requested election of species for prosecution on the merits, applicant provisionally elects Species 2 (means for moving the polishing pad in a linear motion), claims 1-20 with traverse.

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The bases for the applicant's traverse of the Examiner's restriction requirement are respectfully submitted in the Remarks section beginning upon page 3 of this response.

